

Optical coating systems and processes

complete solution for the production of high end
optical coatings

Optatec 2008, 17th June 08



LEYBOLD OPTICS

Dr. Karl Matl

Leybold Optics GmbH

LEYBOLD OPTICS - At a Glance



LEYBOLD OPTICS

- Headquarters Alzenau, Germany
- Shareholder EQT, Sweden
- Employees 430 (260 at Headquarters)
- Subsidiaries
 - EUROPE: Benelux, France, Germany, Italy, Liechtenstein, Spain, Sweden, UK
 - AMERICAS: USA
 - ASIA: China, Japan, Korea, Taiwan
- Sales appr. € 120 Mill. (2007)
- Products Thin Film Coating Equipment and Customer Support
- Applications Ophthalmics, Precision Optics, 3-D coatings, Web, R&D - and Special Systems (Dresden), Display, Architectural Glass, Solar (sputtering, PECVD).



Global Reach



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Germany
Alzenau-HQ



Germany
Subsidiary
Dresden



China
Subsidiary



US
Subsidiary



Precision Optics

See the light.

3

SYRUSpro – Evaporation systems portfolio



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SYRUSpro 710



SYRUSpro 1110 DUV



SYRUSpro 1510



SYRUSpro 910



SYRUSpro 1110



See the light.

Optics systems portfolio – Helios und DLCcs

Helios – high precision sputtering system for optical coatings

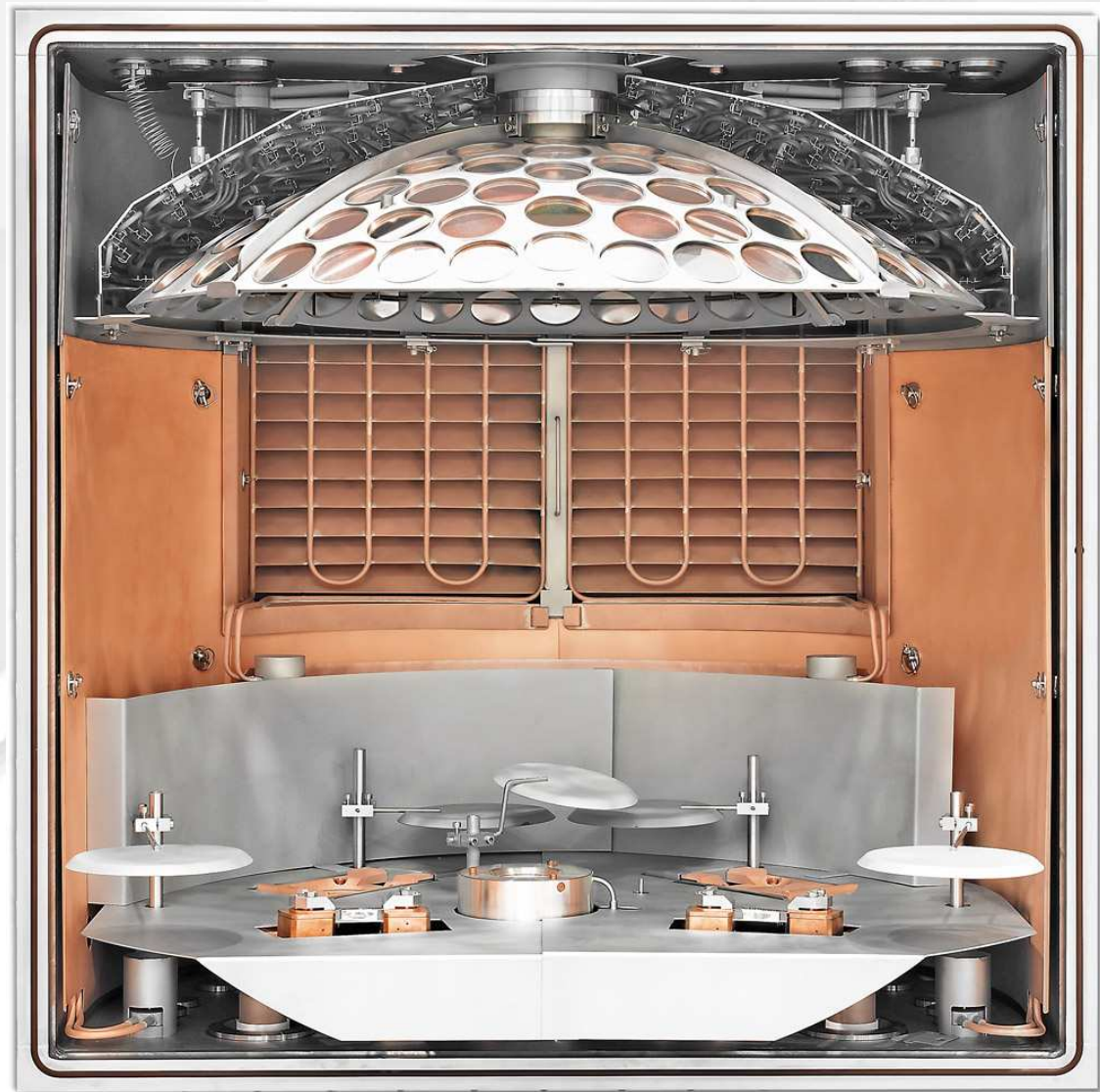


DLCcs – compact PECVD – system für DLC - coatings



System equipment :

- Calotte system – 1000 mm diameter
- APSpro – source
- Evaporator HPE6, 2 pc
- Thermal evaporator, 2 pc
- Heater from top
- OMS - 5000

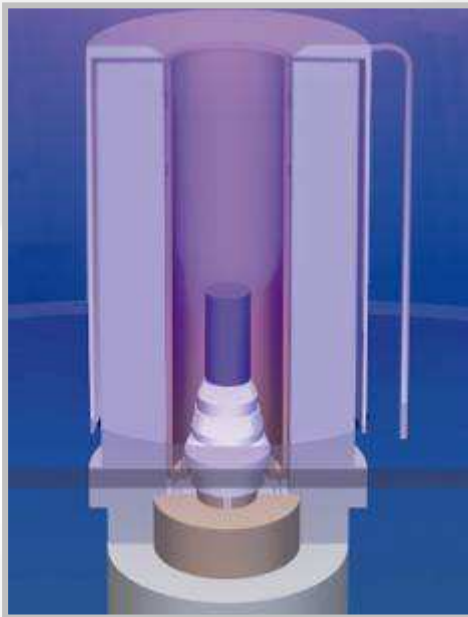


SYRUSpro - 1110



APSprö: High Output Plasma Source

The APSprö - **A**dvanced **P**lasma **S**ource
for deposition of highly dense and
temperature shift-free films with high deposition rates



- Fully dense, shift-free films
- Low temperature for thermally sensitive materials
- Increased wide useful substrate area for excellent distribution over large diameters

Insitu optical monitoring – OMS 5000



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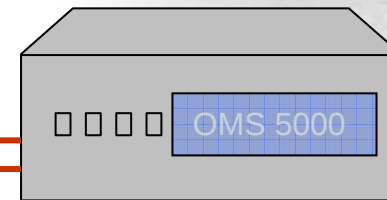
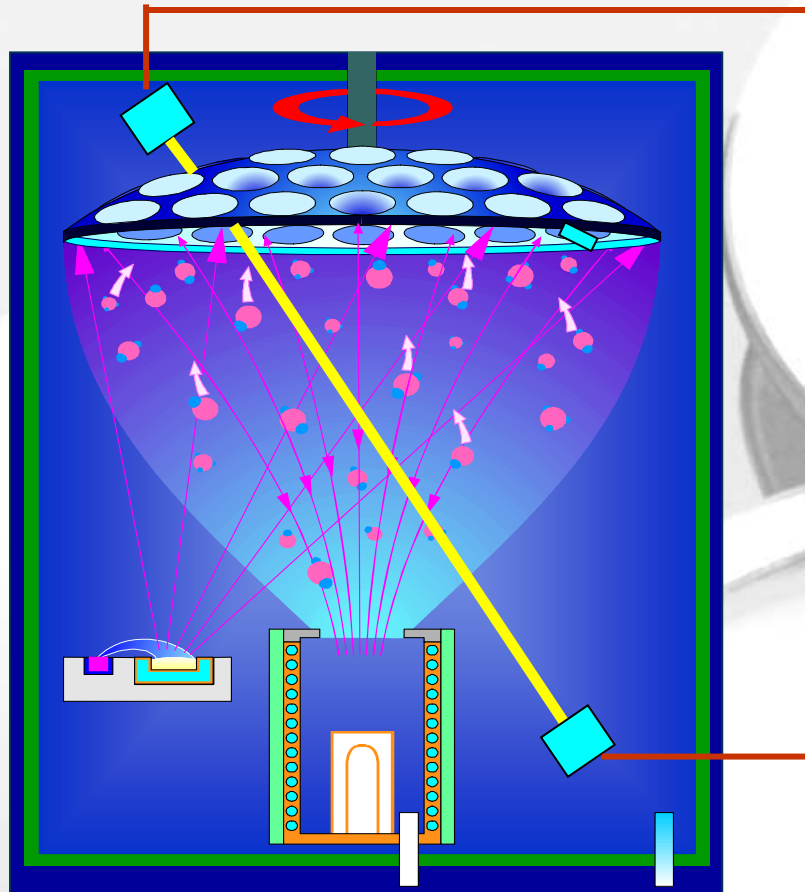
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Motivation :

- Limiting factors in production due to tooling factor between testslide and substrate :
 - accuracy of optical layer thickness on substrate
 - reproducibility from batch to batch
- Next step in innovation :
 - **optical monitoring directly on the substrate on the calotte**
- Breakthrough in accuracy :
 - **Elimination of tooling factor by direct monitoring**

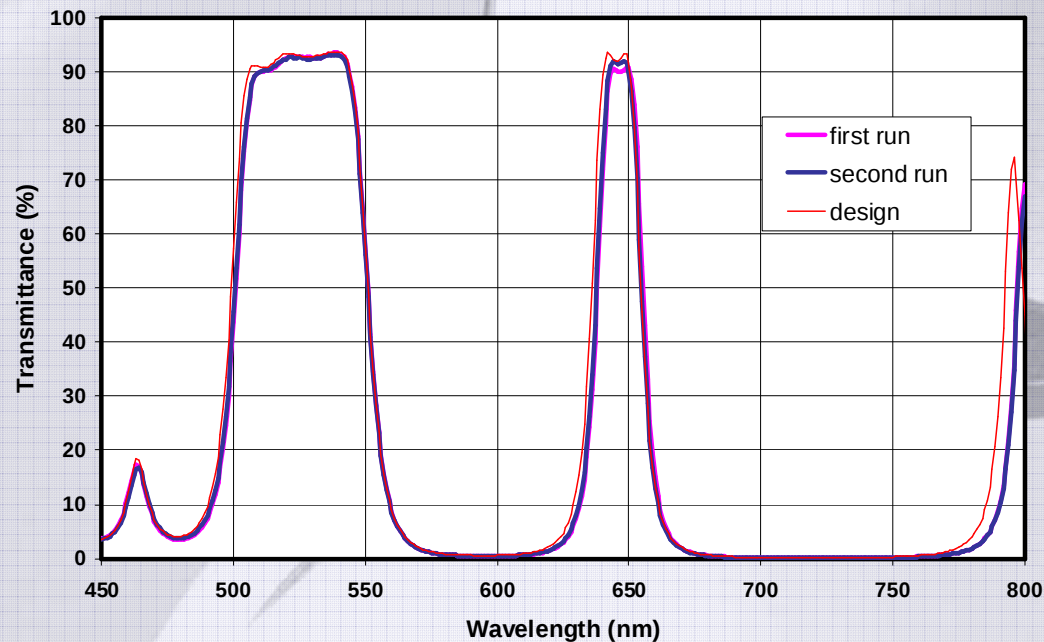
SYRUSpro1100 PIAD Box Coater with direct monitoring in intermittent mode



- Multiple wavelength monitoring on dome
- Transmission measurement with optical fibers.
- Monitor glass located on the substrate holder 330 mm out of center.
- Rotation speed: 30 rpm.

PIAD Box Coater with direct monitoring, coated as designed

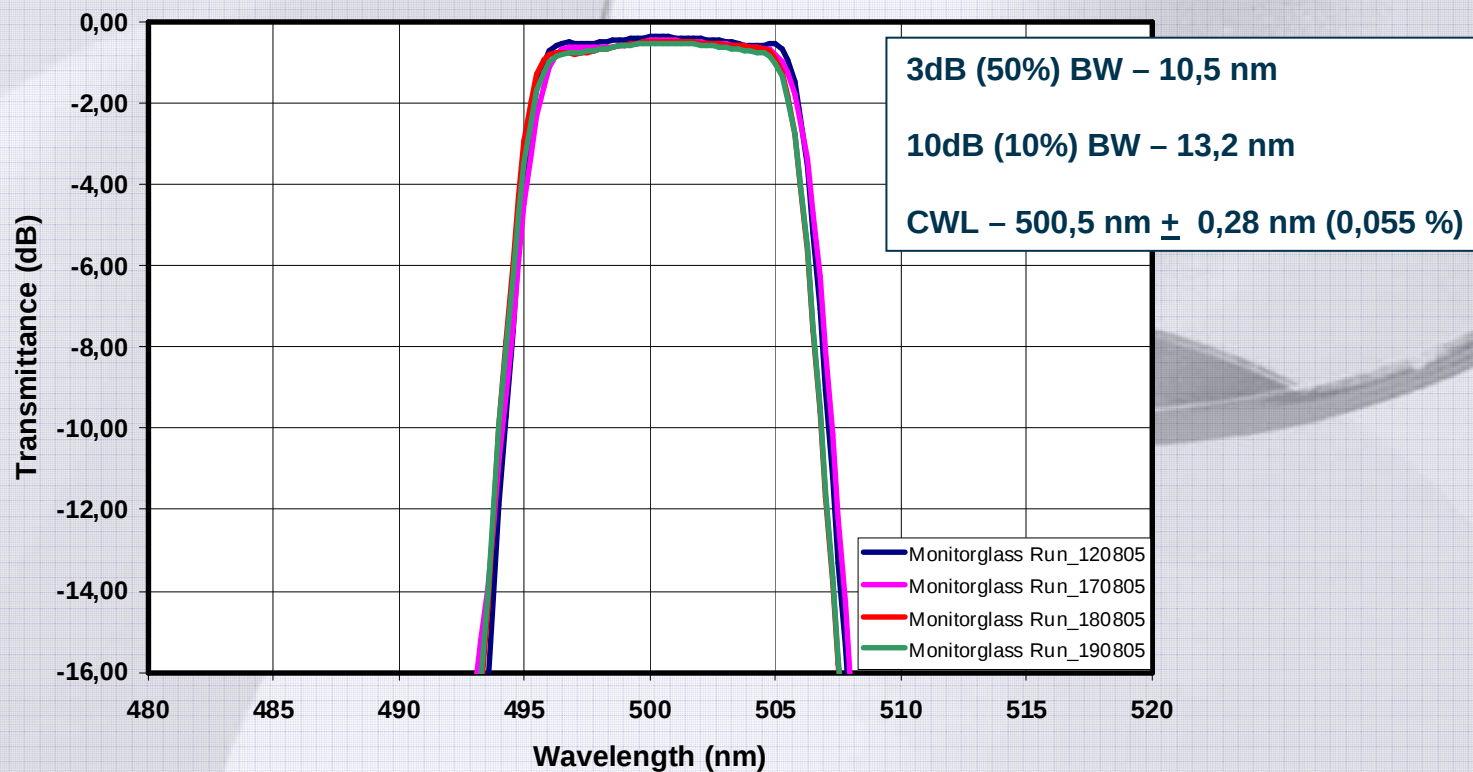
Biosensor Application with $\text{TiO}_2/\text{SiO}_2$ (1st and 2nd Run)



Optical Performance of the monitor glasses on calotte

PIAD Box Coater with direct monitoring

6-Cavity Filter with $\text{TiO}_2/\text{SiO}_2$ (4 consecutive Runs)

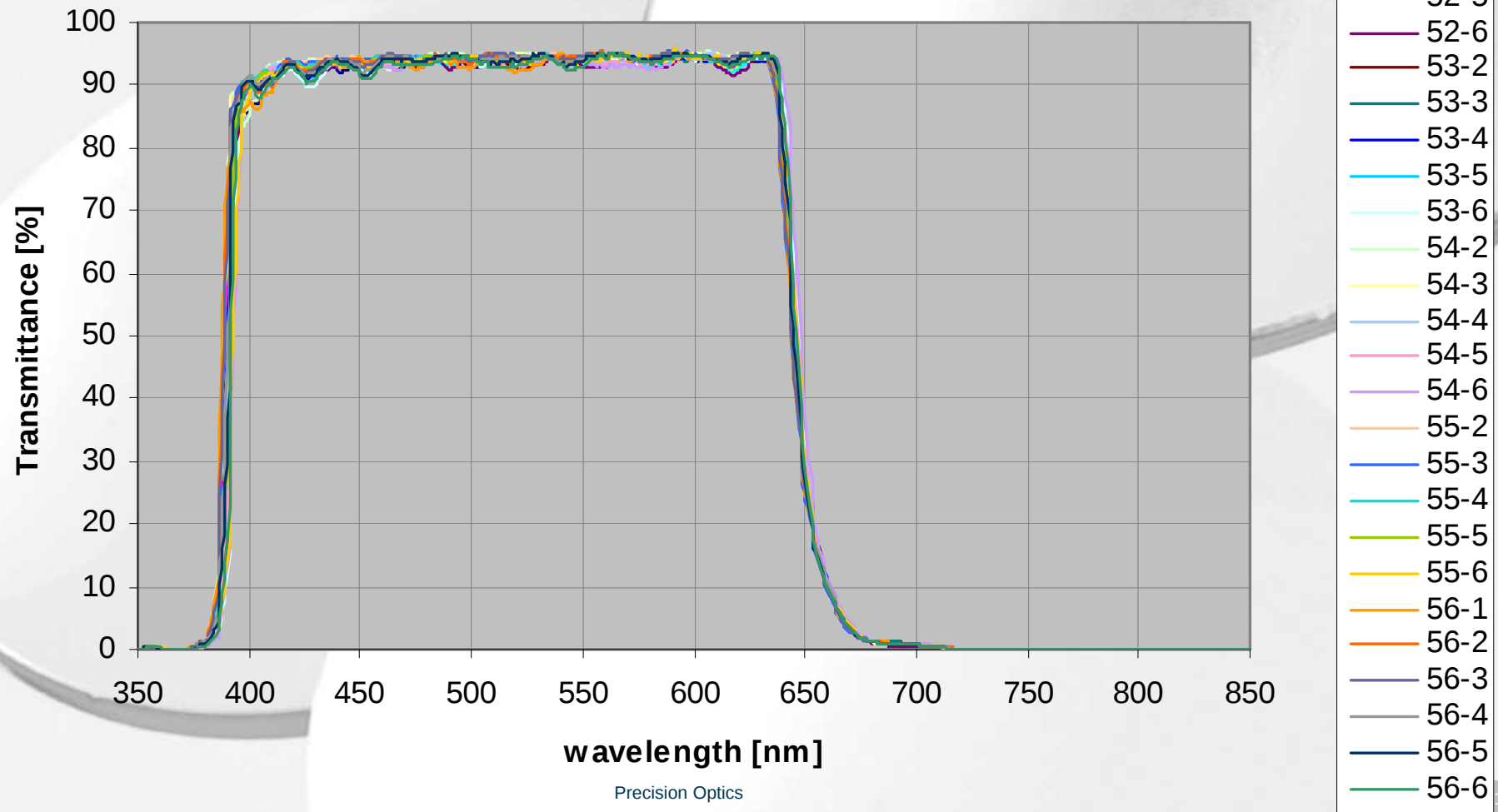


Optical Performance of the monitor glasses on calotte

Direct optical monitoring on calotte, SYRUSpro 1110

■ 5 consecutive batches – all substrate positions (25)

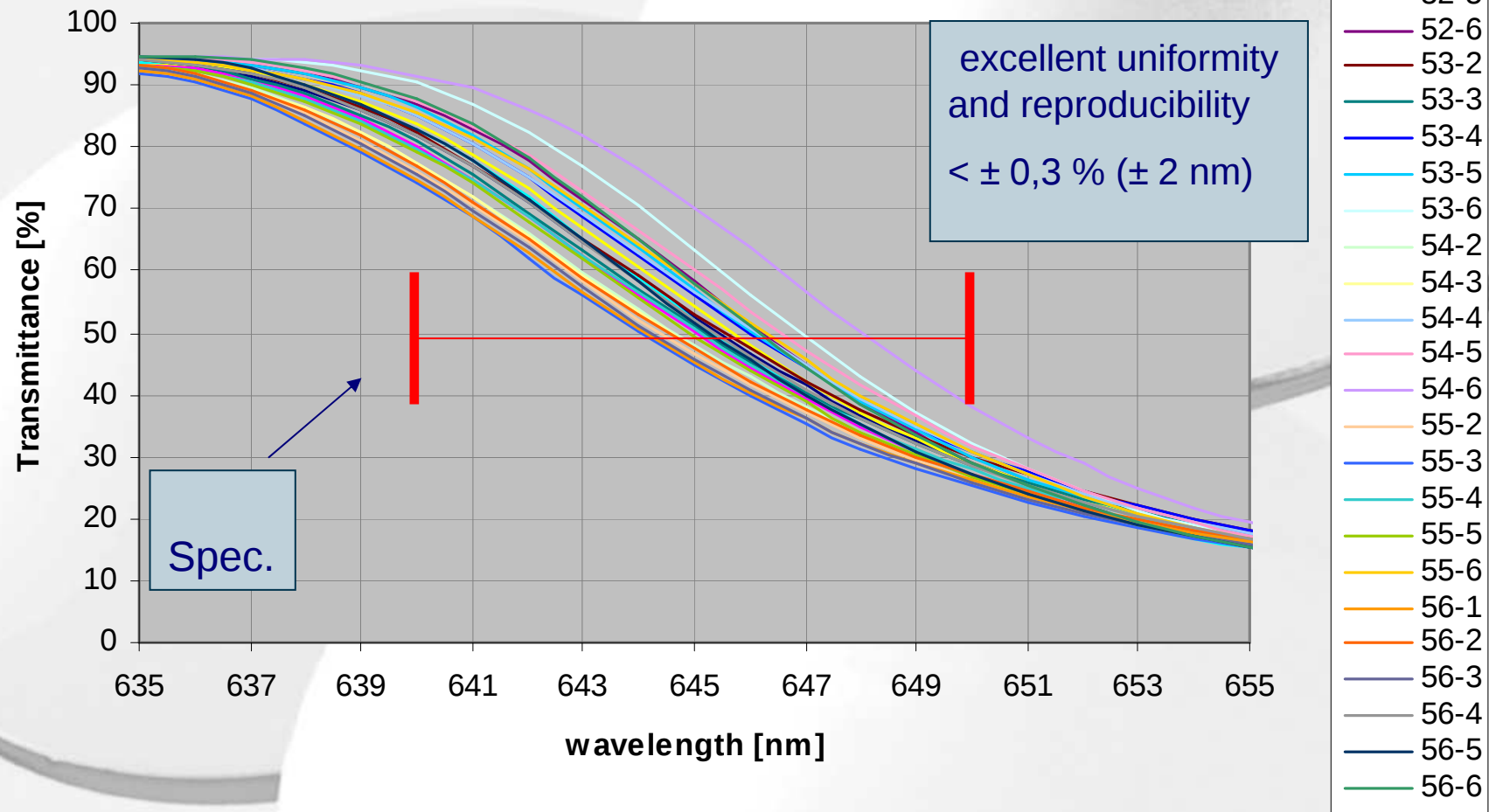
OMS on calotte, 5 consecutive repro - batches



Direct optical monitoring on calotte, SYRUSpro 1110

5 consecutive batches – all substrate positions

OMS on calotte, 5 consecutive repro - batches



Summary :

- Excellent reproducibility was demonstrated with direct monitoring on the testslide on calotte in a SYRUSpro 1100 PIAD Box Coater ($\pm 0,055\%$, 330mm out of center).
- With direct monitoring calibration runs can be widely avoided.
- Uniformity and repeatability achieved was ± 2 nm at 645 nm ($\pm 0,3 \%$) on all radial positions of a 1 m diameter calotte (for IR – cut filter, 40 layers)
- Increased production yield is expected with direct monitoring since a variable tooling factor doesn't exist.
- For optical monitoring with test slide changer, the most unsafe is the outside position with the highest number of substrates, with OMS 5000 on calotte this uncertainty eliminated
- Direct optical monitoring on calotte with OMS 5000 opens new dimensions for accuracy, repeatability and yield in mass production

SYRUS_{pro} 1100 DUV

for 248 nm and 193 nm



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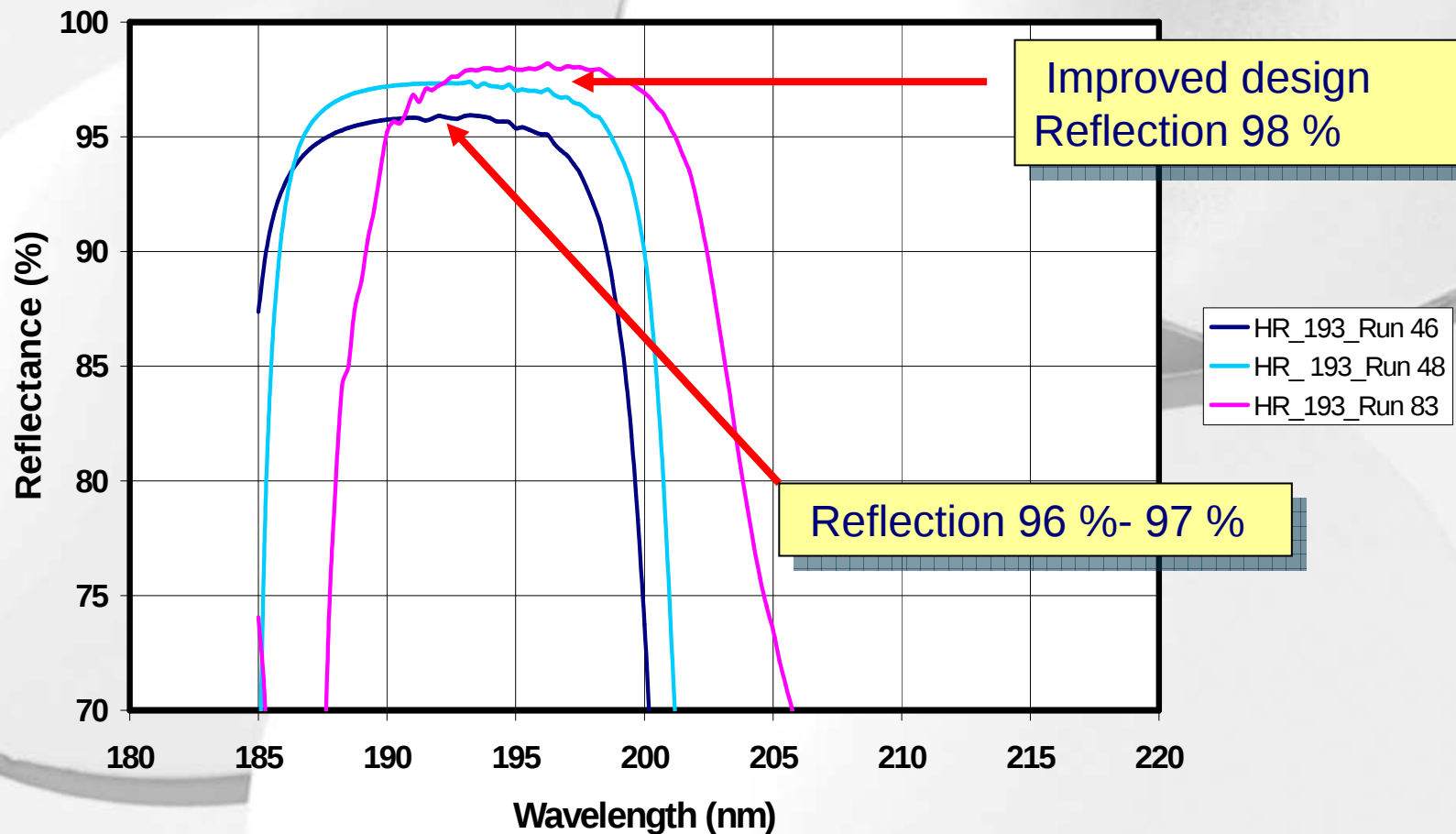
System equipment :

- Planetary system – 400 mm diameter planet plate
- APSpro – source
- Evaporator HPE6, 2 pc
- Thermal evaporator, 2 pc
- Heater from bottom
- OMS - 5000



Low loss, high reflectivity and
environmental stable coatings with APS at 193 nm

APS assisted DUV HR Mirror with Al₂O₃/SiO₂



SYRUS^{pro} 1510

high throughput and high precision



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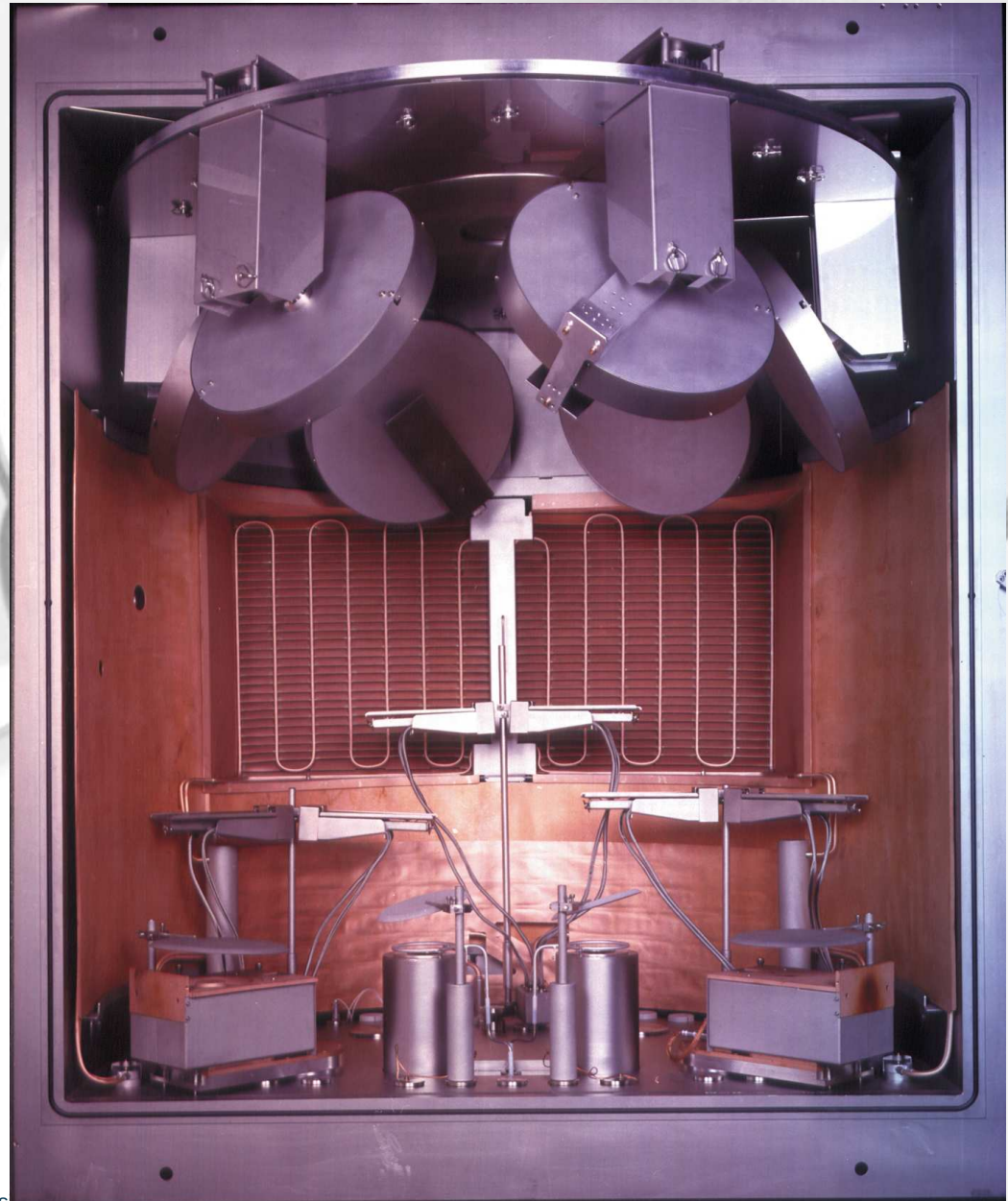
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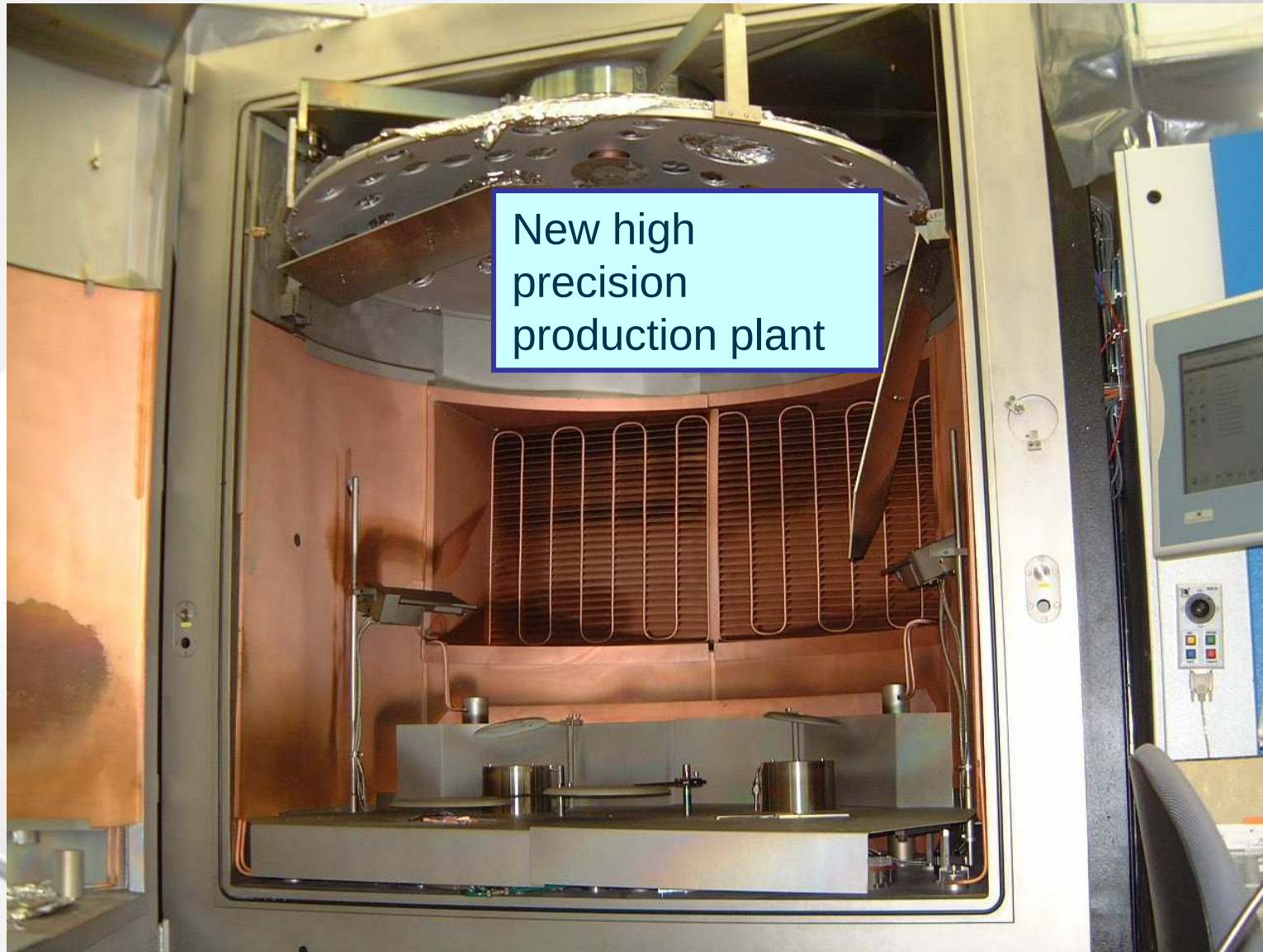
SYRUSpro – 1510 with planetary, system equipment

System equipment :

- Planetary system – 524 mm diameter planet plate, 6 pc
- APSpro – source, 2pc
- Evaporator HPE12/10, 2 pc
- Heater from bottom
- OMS – 5000 with testslide - changer



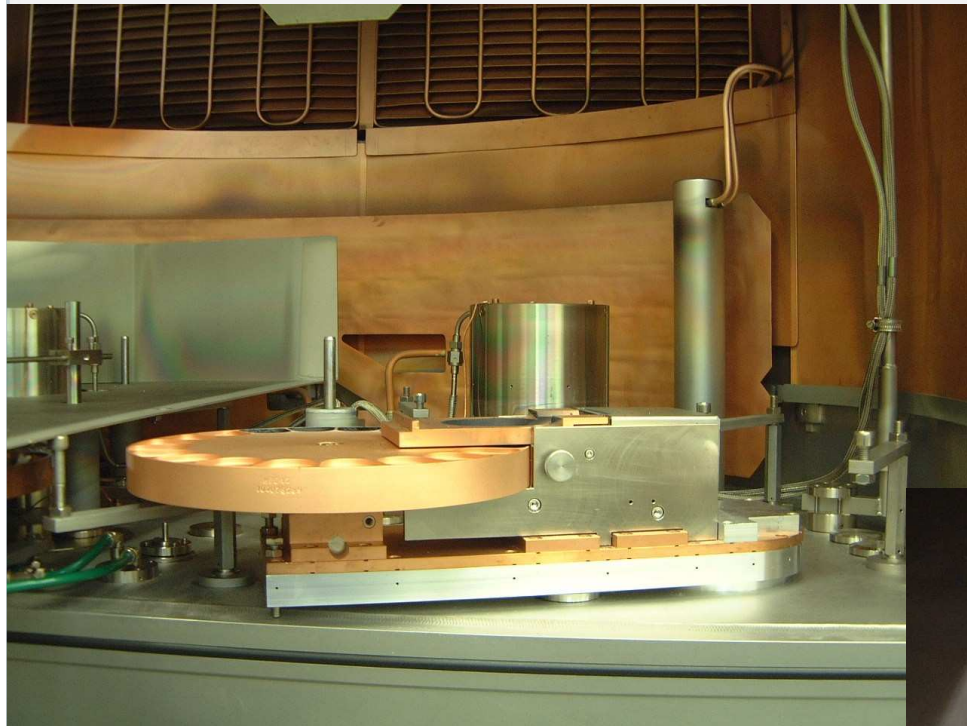
SYRUSpro 1510 with calotte and direct monitoring



HPE 12 – new large volume e – beam gun evaporator

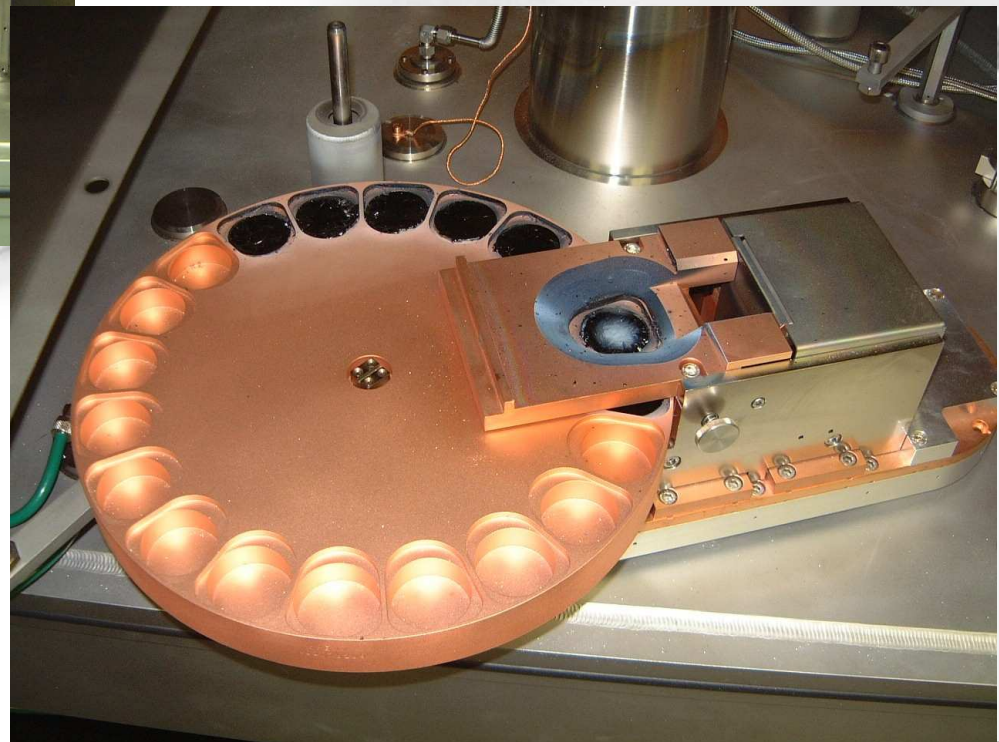


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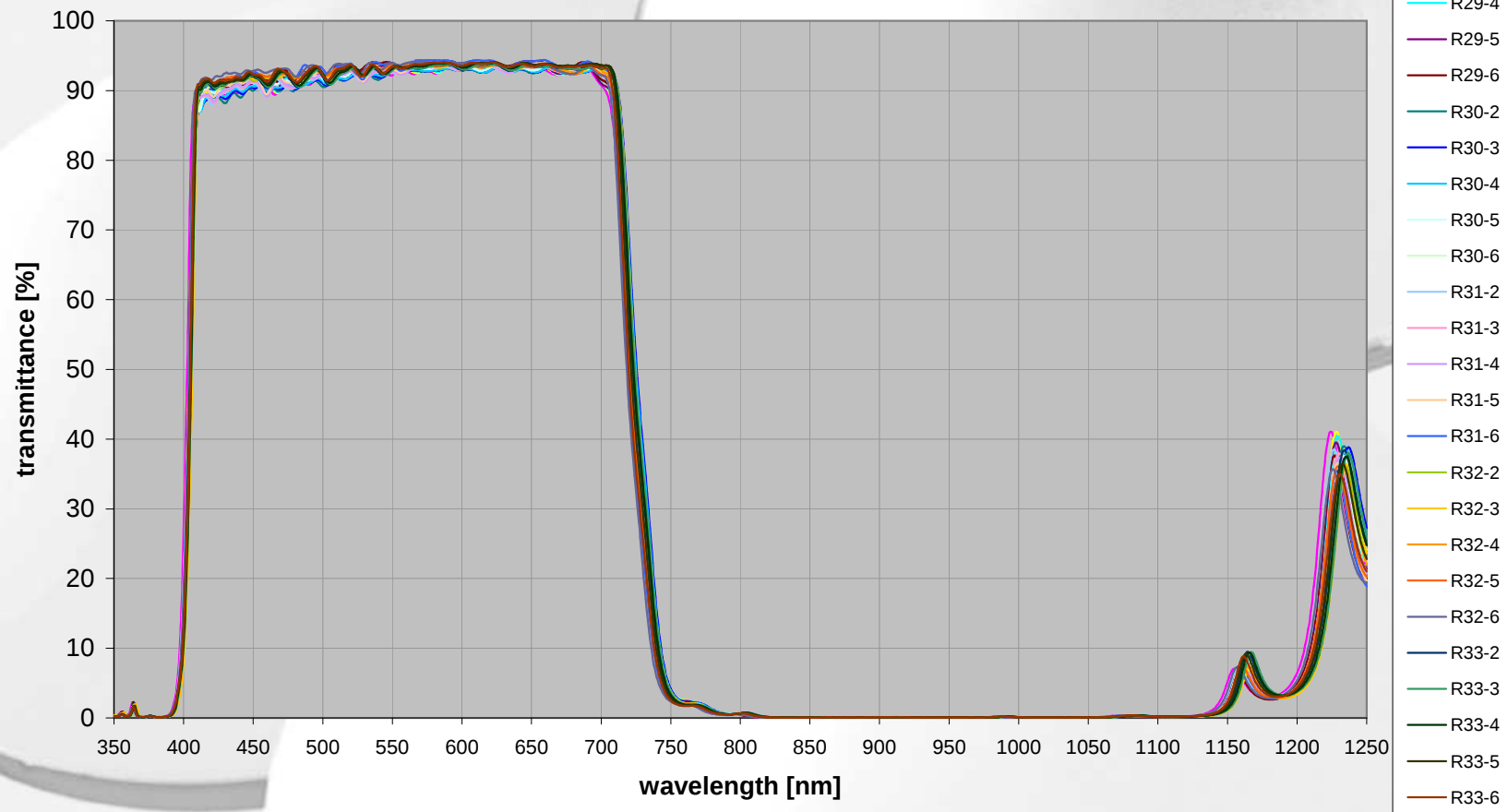
- compact design
- turnable around flange for optimum position

- high volume
20 pockets crucible



■ 5 consecutive batches – all substrate positions (25)

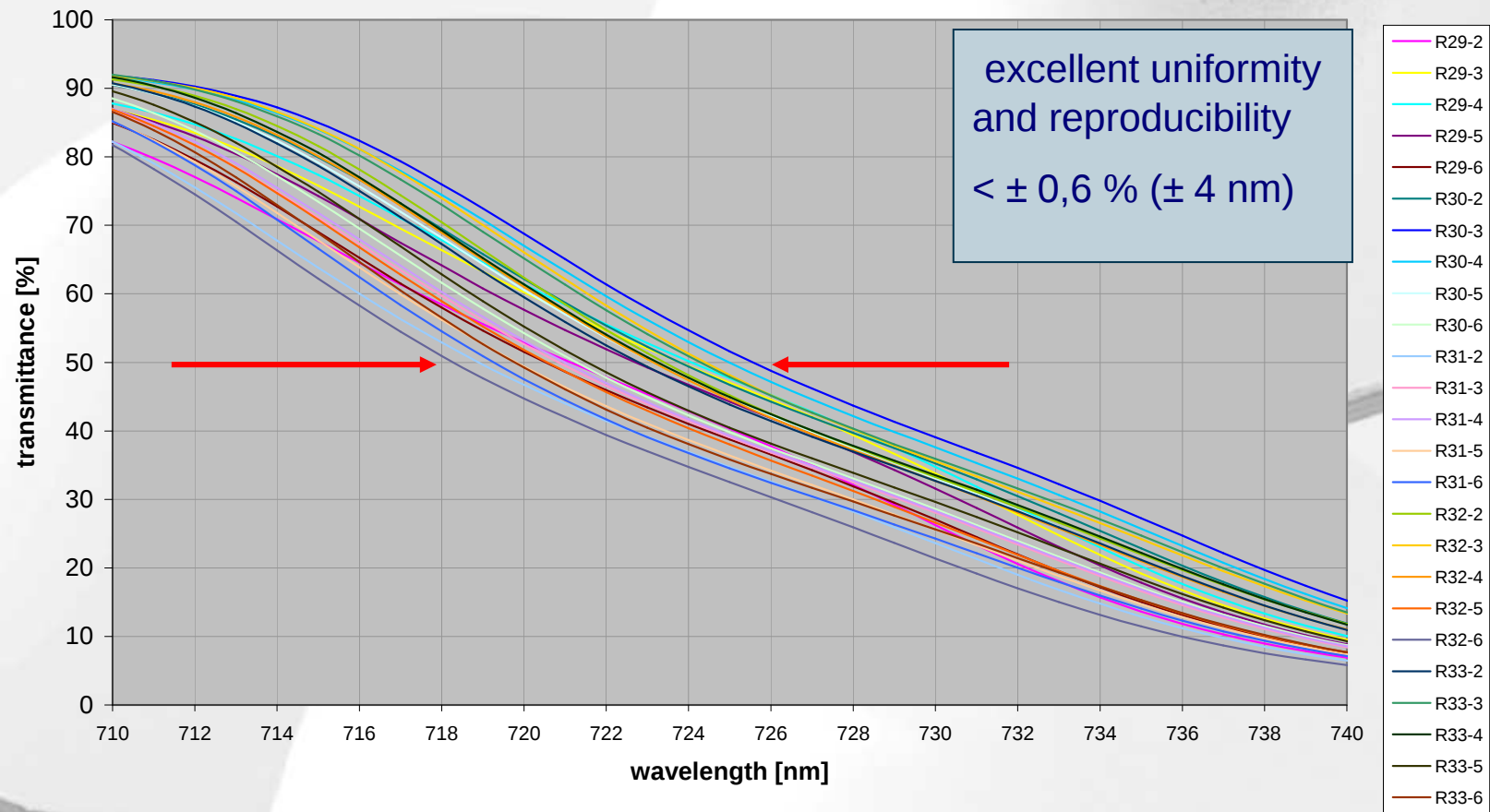
UV - IR - Cut filter, SYRUSpro 1510, Repro Runs #29 - #33



Direct optical monitoring on calotte, SYRUSpro 1510

■ 5 consecutive batches – all substrate positions

UV - IR - Cut filter, SYRUSpro 1510, Repro Runs #29 - #33

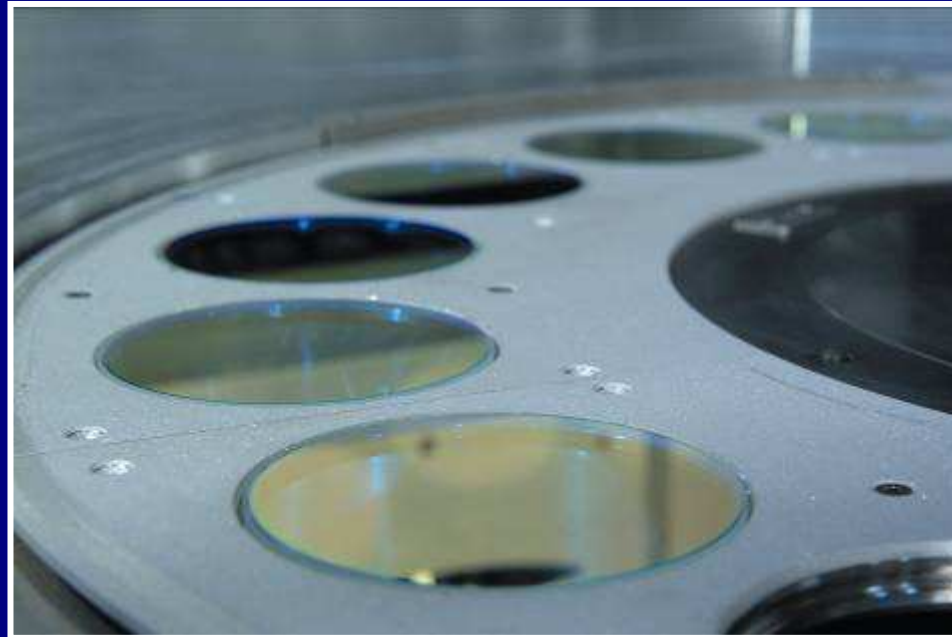


Features of SYRUSpro 1510 for shiftfree filters :

- Equipped with a full high precision calotte (diameter 1400 mm), movable uniformity masks
- New e – beam – gun evaporators HPE 12 for large volume
- Direct optical monitoring on calotte with OMS 5000 installed, for highest accuracies in repeatability and uniformity over the calotte
- APSpro plasma sources for highest deposition rates and excellent layer quality

HELIOS

High precision thin film filter production
by magnetron sputtering



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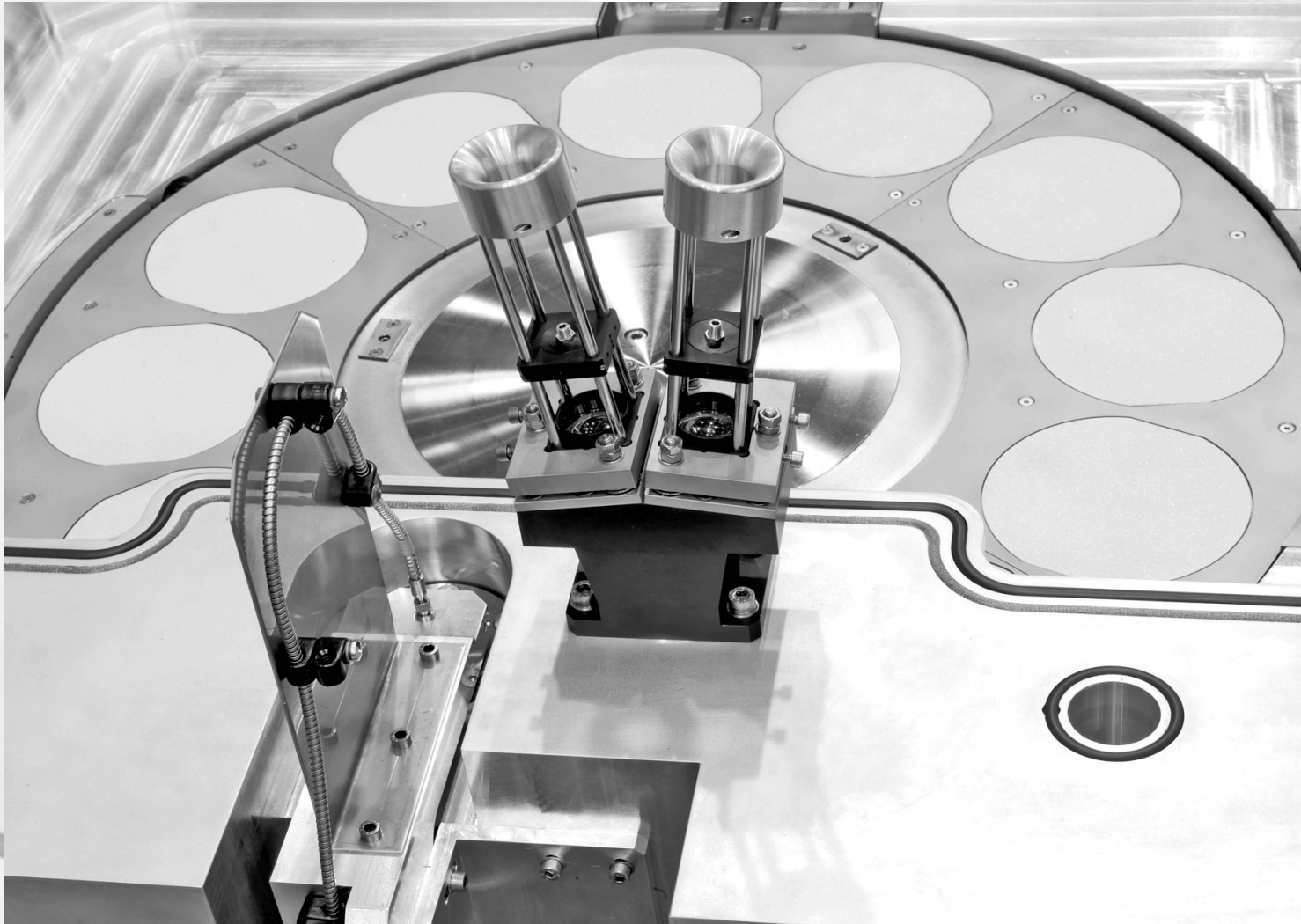
HELIOS Technology

- Magnetron Sputtering with 2 MF Dual Mag
 - Plasma Assisted Reactive Process
 - Sputtering from Metal Target or DC-conducting Oxide Target
 - 1 Dual Mag for high - , 1 Dual Mag for low Index material
 - Co-sputtering with 2 Dual Mag for medium indices
- Dynamic Deposition on rotating Substrate Turn-table
- In-situ direct on Substrate Optical Thickness Control
- Load Lock with automated Single Substrate Handling System

- **Helios with automated single substrate load lock**
 - Door in service position for cleaning, shutter open



- **Helios with automated single substrate load lock**
 - substrate holder and OMS 5000 in transmission and reflection



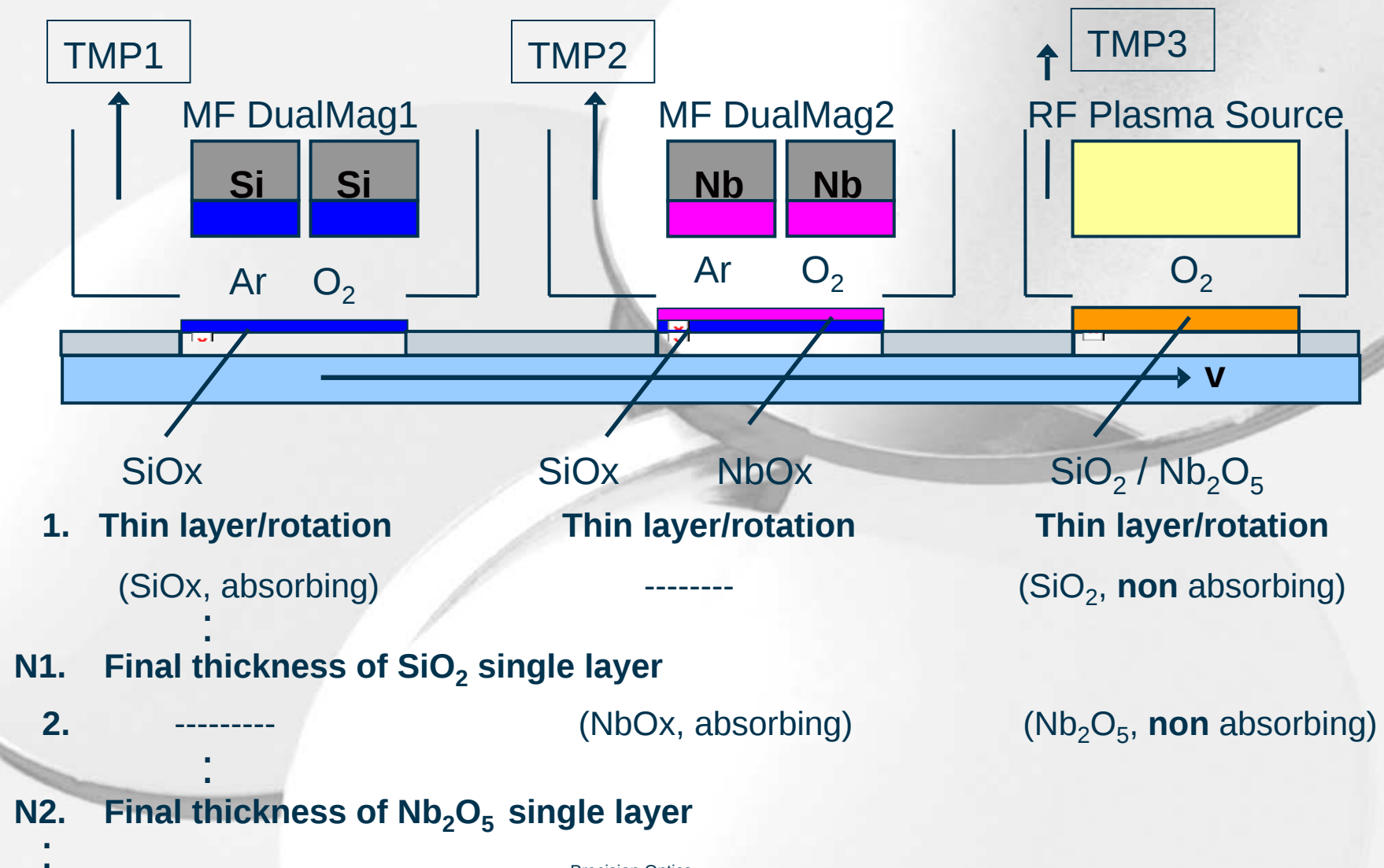
Precision Optics

- **Helios with automated single substrate load lock**
 - view into the load lock with single substrate holder



Precision Optics

Reactive Assist Process with RF – Plasma Source



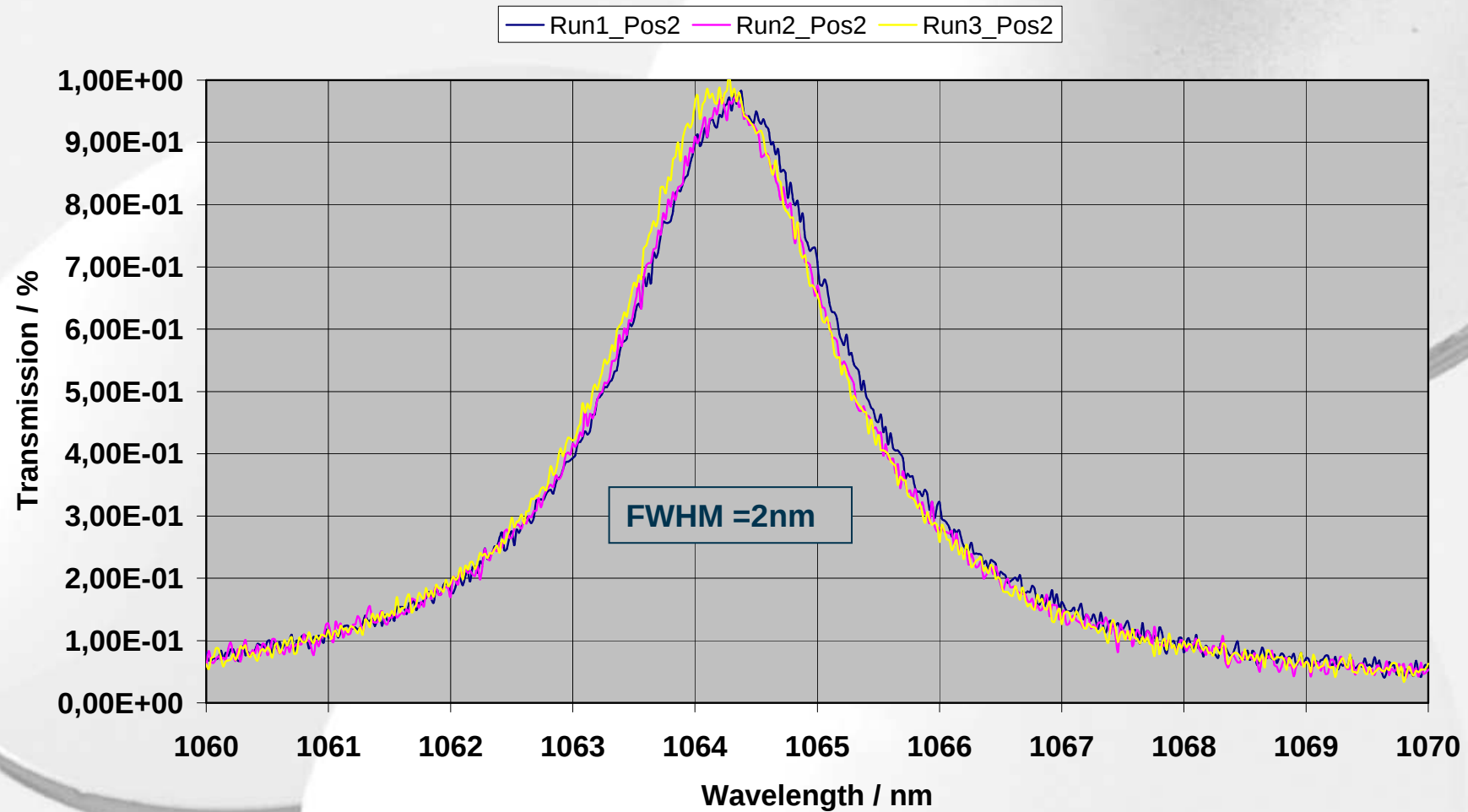
■ Layer Results

- Optical properties, surface roughness and dynamic deposition rate of 500 nm thick single layers.

Material	Ref. index n @ 550nm	Roughness RMS [nm] (Si 0.1)	Rate [nm/s]
SiO ₂	1.485	0.36	0.45
Ta ₂ O ₅	2.17	0.21	0.6
Nb ₂ O ₅	2.37	0.25	0.55

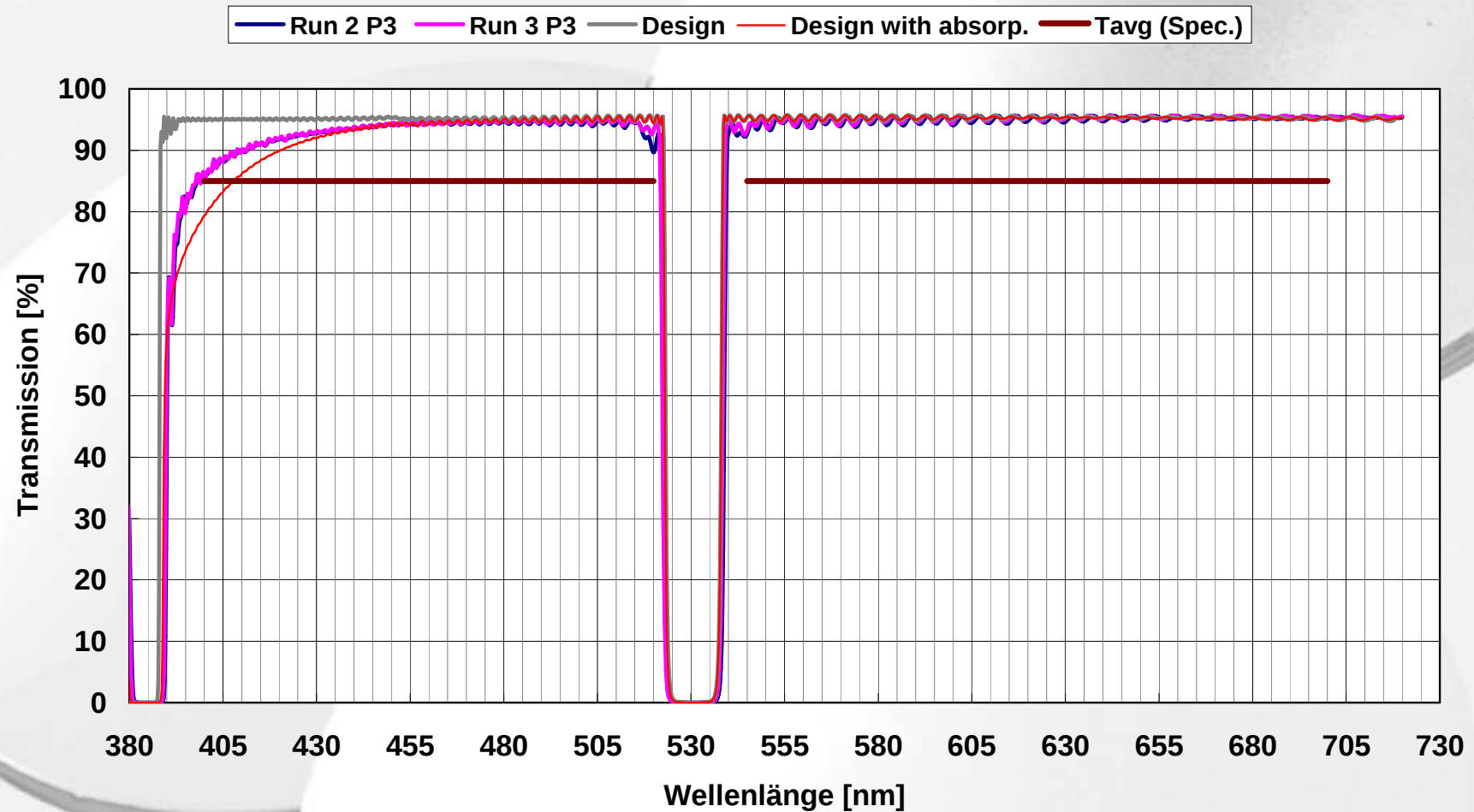
■ Results of NBPF Runs at 1064nm (Result with OSA)

Repro on Monitoring Position P2 of 3 Runs



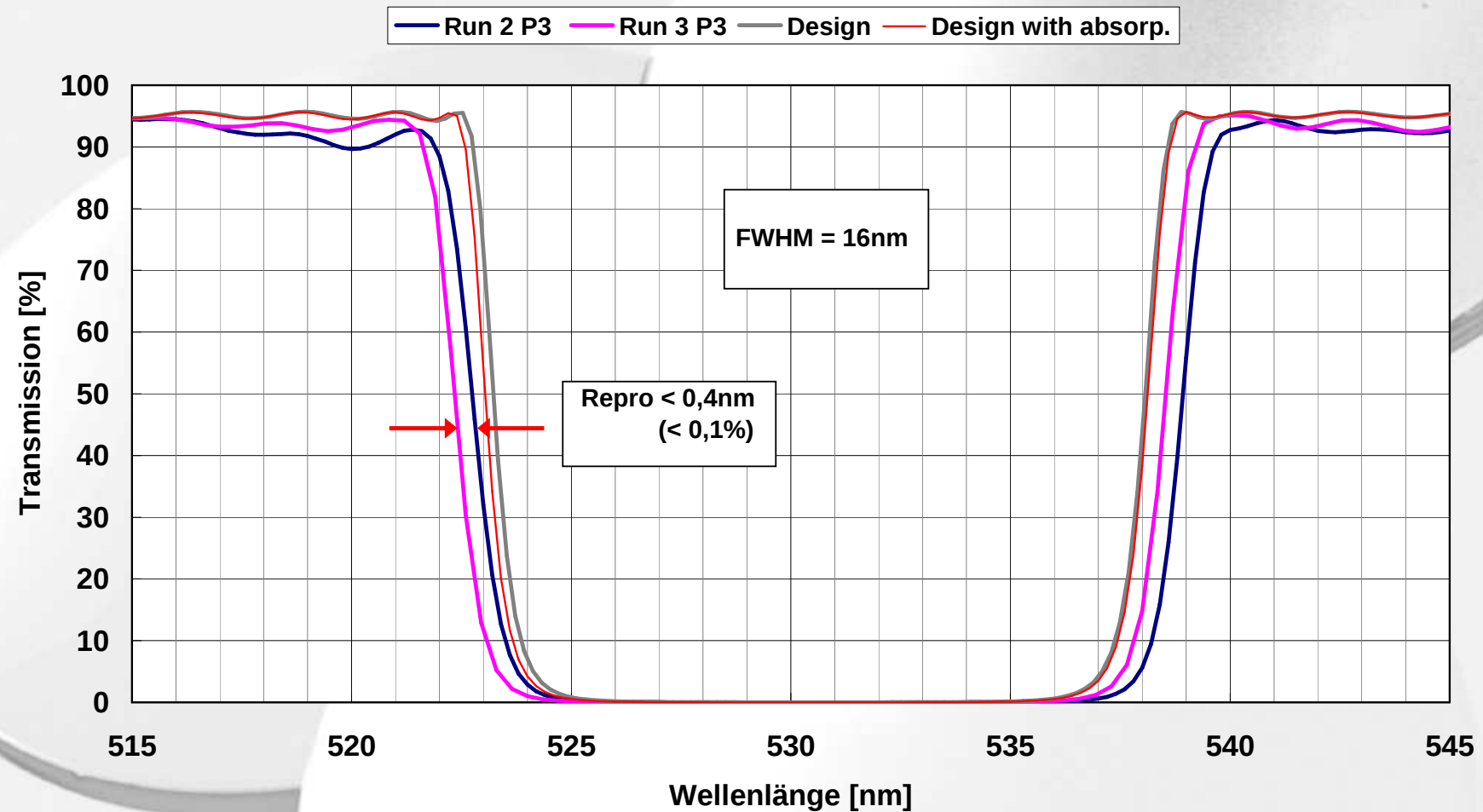
■ Single Notch Filter, *Repro Run to Run* (AOI 0°)

Notch Filter 532nm, OD >4, Repro Run to Run



■ Single Notch Filter, *Repro Run to Run*

Notch Filter 532nm, OD >4, Repro Run



■ Multi_Notch Filter (AOI 10°)

Development done in co-operation with MSO, Jena

Filter Design

- Layer material: Nb₂O₅, SiO₂
- No. of layer: 198
- Total thickness: 20µm
- Thickness Nb₂O₅: > 16µm
- Thickness Control: Optical combined with time

⇒ Total Process Time < 14h

Notch Filter Results

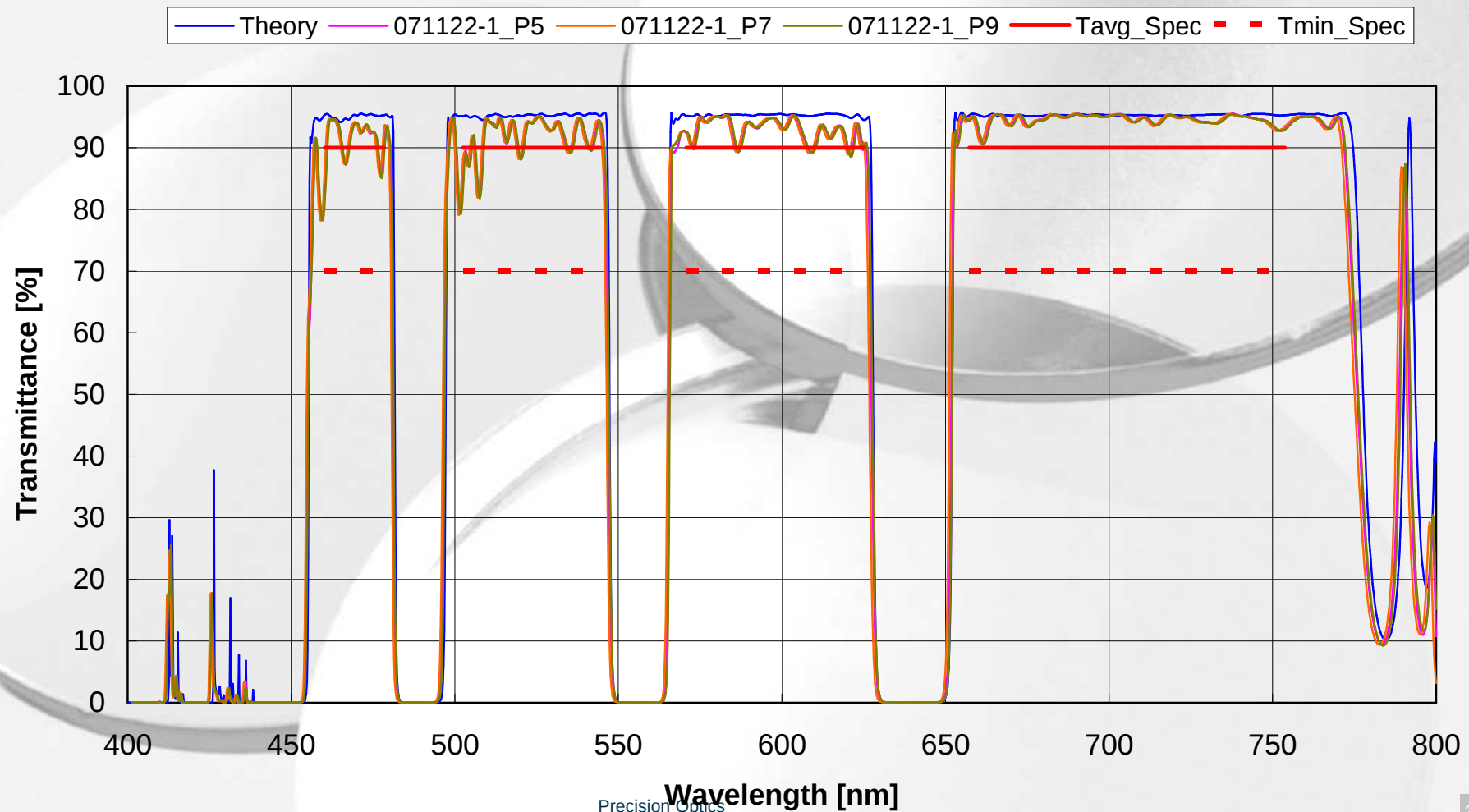


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■ Multi_Notch Filter (AOI 0°),

Development done in co-operation with MSO, Jena

Multi_Notch Filter based on Nb₂O₅/SiO₂ (AOI 0°)



Notch Filter Results

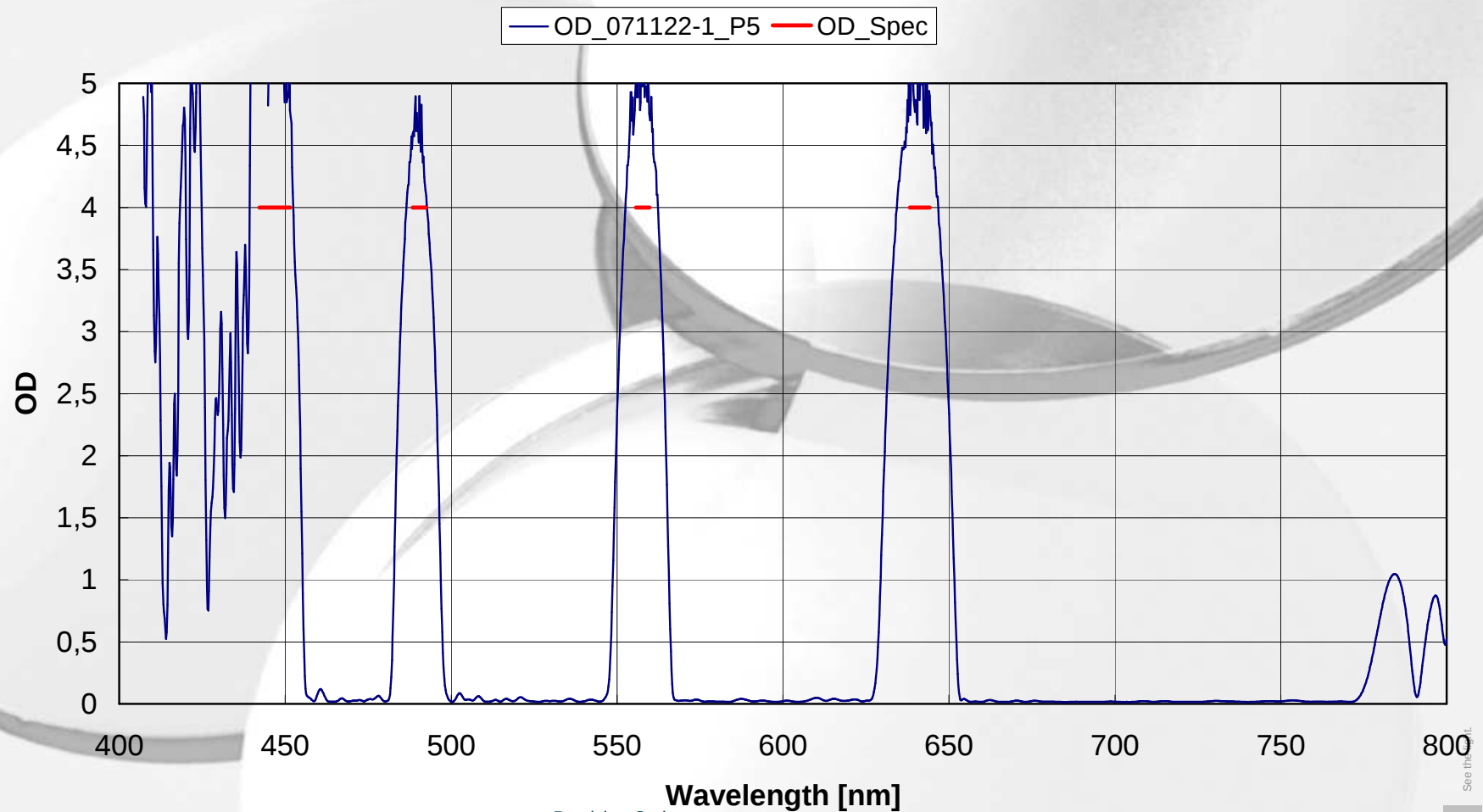


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■ Multi_Notch Filter (AOI 0°)

Development done in co-operation with MSO, Jena

OD of Multi_Notch Filter



Summary Helios

- High quality coatings for classical filter designs by PARMS (Plasma Assisted Reactive Magnetron Sputtering)
- Excellent reproducibility by in-situ direct on-substrate optical monitoring
- Fully automated and clean room compatible production solution with low particle/defect level
- High productivity compared to IBS
- Precise preparation of complex interference filter demonstrated at various notch filter designs

Complete Solutions for the production of high end optical coatings

- LO is providing coating systems for applications from DUV to VIS, NIR to IR
- We have developed our own components, optimized for the process requirements
- Our coatings systems are modular, the standard components are selected according to the process requirements
- LO is providing the coating system and the process according to customer's requirements. The function of the machine and the process will be set up and demonstrated, also at customer's site
- After the process installation finished, you can start with production



***Thank you very much
for your attention !***

***More Questions, interested ?
Please visit us on our booth***

F 38 in Hall 3.0

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